

ABSTRACT OF THE DISCLOSURE (FIG. 6)

"TREATMENT APPARATUS, TREATMENT METHOD,
AND IMPURITY REMOVING APPARATUS"

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A treatment apparatus for treating a substrate in
an isolated treatment space in an air-conditioned clean
room, comprising a removing unit including a plurality
of removing sections for recovering at least some of
10 air in the treatment space and removing impurities from
the recovered air, the removing sections being arranged
in series and each including a supply mechanism for
supplying an impurity remover capable of removing the
impurities by touching the recovered air, a temperature
15 adjustment unit for adjusting the temperature of the
air cleared of the impurities by the removing unit, and
a return circuit for returning the air, adjusted in
temperature by the temperature adjustment unit, to the
treatment space.

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